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Applicant(s): Yoshiro TSURUGIDA

Docket No.
OKI.291Serial No.
10/034,379Filing Date
01/03/2002Examiner
DAVID NHUGroup Art Unit
2818

Invention: METHOD FOR SELECTIVELY OXIDIZING A SILICON WAFER

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SUPPLEMENTAL AMENDMENT

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Serial No. 10/034,379
OKI.291
Amendment dated May 10, 2004

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent application of

Yoshiro Tsurugida

: Group Art Unit 2818

Serial No. 10/034,379

: Examiner David Nhu

Filed January 3, 2002

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METHOD FOR SELECTIVELY OXIDIZING A SILICON WAFER

SUPPLEMENTAL AMENDMENT

U.S. Patent and Trademark Office
2011 South Clark Place
Customer Window, Mail Stop Non-Fee Amendment
Crystal Plaza Two, Lobby, Room 1B03
Arlington, VA 22202

Sir:

Further to the Amendment filed March 24, 2004, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 6 of this paper.